Basic 14 Micro-Nano Tribology

 Ultra low friction of Carbon Nitride (CNx) and Low adhesion and friction of rubber -

Prof. N. Umehara Dept. of Mechanical Science and Engineering, Nagoya University





1.Ultra low friction of Carbon Nitride (CNx)Mechanism

Effect of carbon overcoat on friction

2.Low adhesion and friction of rubber

- High dense plasma irradiation to CIIR
- UV ray irradiation to TPE with PFPE



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1. Ultra low friction of Carbon Nitride(CNx)



A.Y.Liu, M.L.Cohen, Prediction of new low compressibility solids, Science, 245 (1989) 841-842.







Introduction



DLC; A.Erdemir (1991), J.Franks, K.Enke and A.Richardt (1990) H:DLC; A.Erdemir (1999), C.Donnet(1998) a-CNx; N.Umehara, K.Kato(1998)

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Pros - Ultra low friction of Carbon Nitride (CNx) and Low adhesion and friction of rubber

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Hardness: $H_{a-CNx}/H_{a-C}=1.31$ Low friction coefficient(against AI_2O_3/TiC slider)

B.Wei et al. (1998)

Durability: $D_{a-CNx}/D_{a-C}=3\sim4$ (against AI_2O_3/TiC pin) E.C.Cutiongco et al. (1996)





Ion Beam Assisted Deposition



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TEM photo of CNx by IBAD and Hardness





- · Hardness 21GPa
- Amorphous structure
 N=C bonds
- 38) Micro-wear Mechnaisms of Thin Hard Coatings Sliding against Diamond Tip of AFM, ASME, Advances in Information Storage Systems, <u>9</u> (1998)289-302.
 K. Kato, H. Koide, and N. Umehara





Effect of ambient gas on friction coefficient



(N. Umehara and K. Kato, 1998)

Running-in is important for ultra low friction of CNx. Something changed during running-in.





Raman spectroscopy after running-in



Large I_D/I_G provides small friction coefficient

Increase in the number or size of small graphitic domain

N. Umehara, M. Tatsuno, K. Kato, Proc. Int. Trib. Conf. Nagasaki(2000)1007.





XPS before and after running-in



(a) a-CNx coating

(b) wear track after 240 cycles in N₂ gas

After running-in in N₂ gas, C=N increases larger than C-N.





Depth profile of N after running-in in various environment



Tokoroyama, Umehara, IIP Session, Annual meeting of JSME, Sept. 11,2007



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Self surface modification in the running-in process







Outline & Summary

- 1.Ultra low friction of Carbon Nitride (CNx)
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Enhancement of running-in of CNx

with nm thickness carbon overcoat







Effect of 3nm thickness carbon overcoat on friction of CNx





3nm C + CNx

Proc. ICMDT Sapporo,2007, Tokoroyama, Wang, Umehara, Fuwa



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The expectation of ultraviolet ray irradiation to CNx



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Background –Effect of UV irradiation



Energy of photon
$$E = h v = h \frac{c}{\lambda}$$

h: Planck's constant, v: frequency, *c*: light velocity, λ: wavelength





Experimental – Ultraviolet ray irradiation to CNx coating

Did Nitrogen atoms desorb from CNx coating with UV irradiation?				
Table 1 The energy of each wavelength		Table 2 UV irradiation condition		
Wavelength λ , nm	Energy, kJ/mol	Test pieces	Irradiation time	
365	326	•CN ₀	•60 min	
312	382	•CN _{0.09}	•120 min	
254	469	•CN _{0.12}	•180 min	
		•CN _{0.19}	•240 min	
AES analysis out out of the second se				
N/C ratio: I	N/C=x/1	150 250	350 450 $550Kinetic energy, eV$	
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XPS analysis results

J. M. Ripalda et al. Diam. Relat. Mater. 7(1998) 402-406.



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Experimental of tribological property under N₂



Vacuum chamber	
Strain gauges	Speed Ball control holder motor Si ₃ N ₄ ball

UV irradiation conditions		
Wavelength λ	Irradiation time	
•365 nm	•60 min	
•312 nm	•120 min	
•254 nm	•180 min	
	•240 min	

|--|

Load	0.1 N
Sliding speed	4.19×10 ⁻² m/s
Rotation speed	200 rpm
Rotation radius	2.0 mm
Ambient	Nitrogen





Friction test results under N₂ environment



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The effect of UV irradiation on running-in period



3.4 The effect of UV irradiation on minimum m



As-deposit: $\mu = 0.040 \Rightarrow 312 \text{ nm} - 120 \text{ min}$: $\mu = 0.004$





CN_{0.19}



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Industrial products and issue



Issue: Adhesion to mold or conveying equipment







Why rubber can stick to surface?







Another issue for medicine bottle

Issue:

Strong adhesion of rubber for medicine bottle against mold







Various plasma treatment





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Adhesion force measurement

Adhesion force appartus





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Effect of plasma irradiation on adhesion



Treatment time Ion beam >> surface-wave plasma treatment Surface-wave plasma treatment reduced adhesion almost 0 N between stainless steel ball and CIIR sheet





Contact microscope device



Real contact area



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Effect of real contact area on adhesion





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Surface topography of rubber surface

Sputter coated with platinum for 1 mintues



(a)

The subsurface on the CIIR looks less granular and generally has a smoother shape (c) Growing rougher as the treating time increasing

(d)

Microwave power pattern has changed

- Roughest surface observed



The cross-section FE-SEM micrographs of oxygen plasma treated to CIIR rubber for (a) Untreated (b) 200 W, 5 min (c) 200 W, 10 min and, (d) 200 W 20 min

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Surface roughness of argon plasma treated to CIIR rubber



3D laser scanning microscope images of CIIR sheets after oxygen plasma treatment with 200 W at a gas pressure of 30 Pa for treatment times of (a)1, (b)5, (c)10, and (d)15 min.





Young's modulus of CIIR rubber





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Explanation by the GW model



Comparison between GW model & real contact area (Stainless steel ball and CIIR contact)



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 by Larger E & Roughness Smaller Ar
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Tendency in Medical syringe products



Replacing glass syringes with plastic ones is desired.





Issues in advanced plastic syringe



To design the plastic syringe without the silicone oil





Photochemically fluorination



Effect of Photochemically fluorination on friction

Friction test in flat specimen

W=1 N



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Effect of Photochemically fluorination on friction

Friction test in TPE gasket







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by Larger E 🔿 Smaller Ar, Smaller surface energy

1/4

